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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT(S): Dong-Su Kim

SERIAL NO.: 09/899,784

EXAMINER: Fernando L. Toledo

DATE FILED: July 5, 2001

ART UNIT: 2823

FOR: METHOD OF FABRICATING SILICA MICORSTRUCTURES

CERTIFICATE OF MAILING UNDER 37 CFR §1.8

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to the MAIL STOP DD, COMMISSIONER FOR PATENTS, P.O. BOX 1450, ALEXANDRIA, VA. 22313 on June 17, 2004.

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[Signature]
(Signature and Date)

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P.O. Box 1450
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Sir:

INFORMATION DISCLOSURE STATEMENT

In accordance with Applicant's and Applicant's representatives' Duty of Disclosure under 37 CFR § 1.56, and pursuant to 37 CFR §1.97 and MPEP 717.05(b), Applicant(s) submit herewith documentary information for consideration by the Examiner. Information herein cited is only set forth in fulfillment of Applicant's duty of candor in disclosing all information brought to his attention, and is not an admission that it can be used adversely. The publications forwarded herewith are listed on the enclosed Form PTO-1449. Applicant(s) request that the Examiner, upon reviewing the enclosed materials, initial the enclosed form and return a copy thereof in accordance with the instructions on the form.

Enclosed please find copies of 2 U.S. Patents, 1 Foreign Patent and 1 Article listed on the attached Form PTO-1449 and a Summary of Invention. A check in the amount of \$180.00 is enclosed to cover the cost for submission of the Information Disclosure Statement. Please charge any additional fees or credit any overpayment to the undersigned firm's Deposit Account No. 502-470.

06/24/2004 ZJUHA1 00000008 09899784

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Respectfully submitted,

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Sheet 1 of 1

Form PTO-1449 IRSY. 7.801 U.S. Department of Commerce Patent and Trademark Office	ATTORNEY DOCKET NO.	5000-1-212
	SERIAL NO.	09/899,784
LIST OF DOCUMENTARY INFORMATION CITED BY APPLICANT (Use several sheets if necessary)	APPLICANT	Dong-Su Kim
	FILING DATE	July 5, 2001
	GROUP	2823

U.S. PATENT DOCUMENTS

EXAMINE R INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE
	AA	5,847,454	12/8/98	Shaw et al.	257	734	9/22/94
	AB	6,009,218	12/28/99	Grand et al.	385	14	5/22/97

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION YES NO
	AC	2002156745	5/31/02	Japan	G03F	7/00	X

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	AD	"Fabrication of Multi-Layer Substrates for High Aspect Ratio Single Crystalline Microstructures;" C. Gui et al.; 1998, 6 pages.
EXAMINER:		DATE CONSIDERED:
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.		